

# Emil Agocs

## List of Publications by Year in descending order

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24  
papers

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citations

1039406

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h-index

1058022

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g-index

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all docs

24  
docs citations

24  
times ranked

280  
citing authors

#	ARTICLE	IF	CITATIONS
1	Concordant element of the oxidation kineticsâ€™ Interpretation of ellipsometric measurements on Zr. Applied Surface Science, 2022, 573, 151543.	3.1	3
2	Whether Ge-Rich ZrO2 and Ge-Rich HfO2 Materials Have Similar Reaction on Annealing Treatment?. ECS Transactions, 2020, 97, 49-60.	0.3	0
3	Whether Ge-Rich ZrO2 and Ge-Rich HfO2 Materials Have Similar Reaction on Annealing Treatment?. ECS Meeting Abstracts, 2020, MA2020-01, 1027-1027.	0.0	0
4	In Situ Characterization of Biomaterials at Solidâ€™Liquid Interfaces Using Ellipsometry in the UVâ€™Visibleâ€™NIR Wavelength Range. Physica Status Solidi (A) Applications and Materials Science, 2019, 216, 1800762.	0.8	3
5	Optical Properties of Oxidized, Hydrogenated, and Native Zirconium Surfaces for Wavelengths from 0.3 to 25â€™Åm â€™ A Study by Ex Situ and In Situ Spectroscopic Ellipsometry. Physica Status Solidi (A) Applications and Materials Science, 2019, 216, 1800676.	0.8	1
6	Spectroscopic ellipsometry of columnar porous Si thin films and Si nanowires. Applied Surface Science, 2017, 421, 397-404.	3.1	16
7	Grating coupled optical waveguide interferometry combined with in situ spectroscopic ellipsometry to monitor surface processes in aqueous solutions. Applied Surface Science, 2017, 421, 289-294.	3.1	7
8	Plasmon-enhanced two-channel in situ Kretschmann ellipsometry of protein adsorption, cellular adhesion and polyelectrolyte deposition on titania nanostructures. Optics Express, 2016, 24, 4812.	1.7	16
9	Porosity and thickness characterization of porous Si and oxidized porous Si layers â€™ An ultravioletâ€™visibleâ€™mid infrared ellipsometry study. Microporous and Mesoporous Materials, 2016, 227, 112-120.	2.2	16
10	Bilayered (silicaâ€™chitosan) coatings for studying dye release in aqueous media: The role of chitosan properties. Carbohydrate Polymers, 2016, 136, 137-145.	5.1	15
11	Doping silica beyond limits with laser plasma for active photonic materials. Optical Materials Express, 2015, 5, 2849.	1.6	14
12	Spectroellipsometric and ion beam analytical studies on a glazed ceramic object with metallic lustre decoration. Thin Solid Films, 2014, 571, 715-719.	0.8	0
13	Composite polymeric-inorganic waveguide fabricated by injection molding for biosensing applications. , 2014, , .		1
14	Approaches to calculate the dielectric function of ZnO around the band gap. Thin Solid Films, 2014, 571, 684-688.	0.8	24
15	Resolving lateral and vertical structures by ellipsometry using wavelength range scan. Thin Solid Films, 2014, 571, 579-583.	0.8	8
16	Characterization of in-depth cavity distribution after thermal annealing of helium-implanted silicon and gallium nitride. Thin Solid Films, 2014, 571, 567-572.	0.8	1
17	Comparative measurements on atomic layer deposited Al2O3 thin films using ex situ table top and mapping ellipsometry, as well as X-ray and VUV reflectometry. Thin Solid Films, 2013, 541, 131-135.	0.8	9
18	Model dielectric function analysis of the critical point features of silicon nanocrystal films in a broad parameter range. Thin Solid Films, 2013, 541, 83-86.	0.8	4

#	ARTICLE	IF	CITATIONS
19	Investigation of thin polymer layers for biosensor applications. Applied Surface Science, 2013, 281, 66-72.	3.1	13
20	Highly transparent ITO thin films on photosensitive glass: sol-gel synthesis, structure, morphology and optical properties. Applied Physics A: Materials Science and Processing, 2012, 107, 385-392.	1.1	15
21	Optical constants of MOCVD-grown Aurivillius phases in the $\text{Bi}_4\text{Ti}_3\text{O}_{12-x}\text{Na}_{0.5}\text{Bi}_{0.5}\text{TiO}_3$ system measured by spectroscopic ellipsometry. Applied Physics A: Materials Science and Processing, 2011, 105, 81-88.	1.1	2
22	Optical characterization of nanocrystals in silicon rich oxide superlattices and porous silicon. Thin Solid Films, 2011, 519, 3002-3005.	0.8	12
23	Characterization of damage structure in ion implanted SiC using high photon energy synchrotron ellipsometry. Thin Solid Films, 2011, 519, 2791-2794.	0.8	3
24	Spectroscopic ellipsometry studies on the optical constants of $\text{Bi}_4\text{Ti}_3\text{O}_{12-x}\text{Na}$ thin films grown by metal-organic chemical vapor deposition. Thin Solid Films, 2011, 519, 3782-3788.	0.8	6